SNF FY20 Lab Use Rates

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	Equipme			
Lab	Rate Class	Academic ³	Industry ³	Industry: SBIR ³
Cleanroom ²	Base Rate \$/hr < Soft Cap	\$50	\$135	\$110
	Monthly Soft Cap	\$3,500	\$13,500	\$11,000
	Above Soft Cap	25% of hourly rates		
	Epitaxial Deposition (Epi2/2B)	\$70.00	\$140	\$112
ExFab ^{4,5}	1	\$3	\$9	
	2	\$5	\$15	
	3	\$10	\$30	
	4	\$20	\$60	
	5A	\$35	\$105	
	5B	\$35	\$70	
	Raith	\$70.00	\$140	
MOCVD ⁴	MOCVD	\$100	\$240	
	Other	Fees ¹		
Service	Description	Rate		
Staff Support	Training Recharge \$/hr	\$80.00		
	Staff Support \$/hr	\$80.00		
Stores	Inventory / Subscriptions	Refer to Stores price list sheets		

- (1) **FY20 Rates:** Badger reports direct costs, as per this rate sheet. Additional Facilities & Administration (F&A) overhead (https://doresearch.stanford.edu) is applied to invoices. In FY20, U.S. academic and government organizations are subject to 8% F&A; all other external entities are subject to 57.7%.
- (2) Cleanroom Soft Cap: Cleanroom tools come under the Soft Cap fee structure. The exceptions are:
 - a. Epi2/2B are excluded from the Soft Cap and charged on a straight hourly basis.
 - b. **Precious Metals** use is charged by gram and based on the weighted market price for this year, rounded up to the nearest \$1: Gold-\$42; Platinum-\$27, Iridium-\$48; Palladium-\$43. Precious metal use is incorporated into the equipment charges for metallization tools.
 - c. No-Charge Tools:
 - i. Analytical tools: microscopes, stylus profilometers (p2, alphastep), nanospecs, surfscan4500
 - ii. Ovens: 90C post-spin bake, 110C pre-bake, 150C singe, BlueM programmable and white-oven
 - iii. Solvent benches: no charge for rinsing & soaking; charge for module (heaters, sonicators).
 - iv. Miscellaneous: mask cleaner, uvcure
- (3) Rate Categories: Academic rates apply to: Stanford/SLAC, non-Stanford academic institutions, government, not-for-profit entities, and entities covered by SNF Research Participation. Companies supported by a verifiable SBIR award are eligible for the SBIR rate (Cleanroom only.) All other independent entities receive the Industrial rate.
- (4) **ExFab and MOCVD labs:** Soft cap does not apply to these labs. Precious metals are charged as a Stores item as follows: Gold-\$0.92 /nm, Platinum-\$0.59/nm, Iridium-\$1.05/nm, Palladium- \$0.95/nm. MOCVD precursor use in excess of 3 grams per run will be charged at \$40/gram. This fee applies to the following precursors and is incorporated into equipment charges: UDMHy, TBP, and TBAs.

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Area/Equipment	Rate Class	Area/Equipment	Rate Cla	
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Deposition		Characterization		
Aixtron Graphene Furnace	5B	AFM-Asylum	4	
Carbon Nanotube Furnace	5B	AFM #2	3	
Hummer Evaporator	5B	Alphastep Profilometer	No cost	
Parylene Coater	5B	Cytoviva Hyperspectral Analyzer	4	
Lesker Sputter 1/2	5A	Semilab LEI Eddy Current	2	
AJA Evaporator	5A	Jasco-UV/Vis/NIR Spectrometer	4	
		Keyence 3D Microscope	5A	
Patterning		Malvern Dynamic Light Scatter	4	
3D Wax Printer	1	Micromanipulator Probe Station	2	
Form2 3D SLA Printer	1	Nanospec	No cost	
Alveole Primo	4	Biologic	No cost	
Nanoinkjet	3	S-neox	No cost	
Raith EBeam Writer	Raith	Sinton Lifetime Tester	2	
Heidelberg MLA 150 1/2	5A	Hall Measurement System	2	
Nanoscribe 3D Printer	5A	,		
Optomec Aerosol Jet Printer	3	Wet Processing		
Voltera	2	Headway 3 Manual Spinner	3	
		Laurell Develop/Etch Processer	3	
Machining		Micromist Electrospray Coater	3	
Chemical Mechanical Polish	5B	Wet Bench for Develop	3	
DISCO Wafersaw	5A	Wet Bench for Solvents	3	
DISCO Backgrind	5B			
Minitech Micromill	3	Other		
Thermolyne Muffle Furnace	1	Centrifuge	No cost	
Laser Cutter	4	Disperser	No cost	
Modela CNC Micromill	No cost	Flipchip Bonder	5A	
Manual Micro Drill Press	No cost	Oriel DUV	No cost	
		Sonicator	No cost	
Controlled Environment		SCS G3 Spincoater	3	
Fumehood #1-4 1		Thermoscientific Oven	2	
Glovebox-Left/Right	1	Thinky Mixer	3	
	_	Heat Seal Press	No cost	
		Plasma Etcher	4	
		Hotplate-1	2	
		Dry Film Laminator	1	
		Dymax UV Cure	1	
		XPlore Microcompounder	4	
		YES HMDS Prime Oven #2	5A	
	N400175		5.,	
Area/Equipment	MOCVD E	quipment Rate Class		
Aixtron 200 (GaAs)		MOCVD		
Aixtron CCS (GaN)		MOCVD		